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Client/Matter No. 81848.0016.001
Express Mail No. EV331755906US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/546,174

Application of: Chih-Chien Liu, Ta-Shan Tseng, W. B. Shieh, J. Y. Wu, Water Lur and Shih-Wei Sun

Filed: April 11, 2000

Art Unit: 1711

Examiner: Sergeant, Rabon A.

Attorney Docket No. UMC-96-279 CON

For: HIGH DENSITY PLASMA CHEMICAL
VAPOR DEPOSITION PROCESS

Confirmation No.: 4793

Customer No.: 25235

PETITION FOR WITHDRAWAL FROM ISSUE UNDER 37 CFR 1.313

MAIL STOP PETITIONS

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This is a Petition for the Withdrawal from Issuance of Patent Application No. 09/546,174 under 37 CFR 1.313 to permit consideration of newly discovered art in an information disclosure statement. An RCE filing accompanies this petition. The Issue Fee was timely paid on May 17, 2004 but no patent number has been issued to date.

The Petition fee of \$130 is enclosed with this transmittal. No further fee is believed to be required by this Petition. However, should any fee be required, please charge Deposit Account No. 50-1123.

Dated: 10/25, 2004


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